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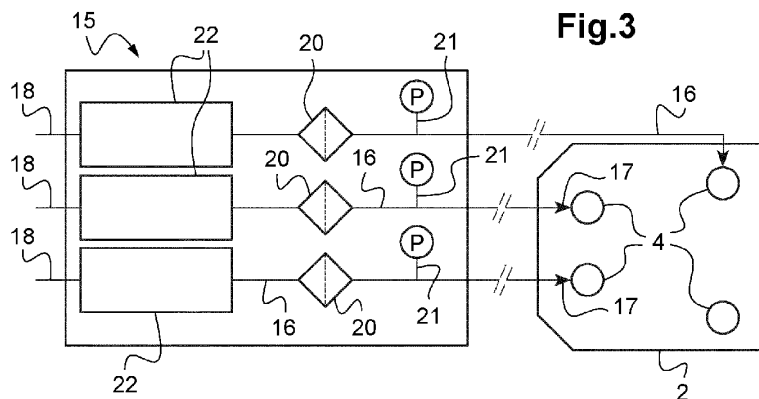
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(54) Title: STATION AND METHOD FOR MEASURING THE PARTICLE CONTAMINATION OF A TRANSPORT ENCLOSURE FOR THE ATMOSPHERIC TRANSPORT AND STORAGE OF SEMICONDUCTOR WAFERS



(57) Abstract: Measurement station (1) for measuring particle contamination in a transport enclosure for the atmospheric transport and storage of semiconductor wafers, comprising a particle counter (5) and an interface (6) designed to be coupled to the shell (2) of a transport enclosure in place of the door (3), said interface (6) comprising a sampling orifice (7) fluidly connected to the particle counter (5), the measurement station (1) further comprising a clean-gas injection device (15) comprising at least one injection line (16) comprising at least one injection nozzle (17) designed to be fluidly connected to a ventilation port (4) of the transport enclosure coupled to the interface (6) for injecting clean gas into the transport enclosure, from outside the transport enclosure, through the at least one ventilation port (4) of the transport enclosure.

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